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PPLICATION N	0. F	ILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO
10/791,190		03/02/2004	Frank L. Hall	4718.3US (00-0316.03/US)	1971
24247	7590	06/28/2005		EXAMI	NER
TRASK	BRITT			HEINRICH, SAMUEL M	
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SALT LAKE CITY, UT 84110				ART UNIT	PAPER NUMBER
				1725	

DATE MAILED: 06/28/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

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	Application No.	Applicant(s)					
	10/791,190	HALL, FRANK L.					
Office Action Summary	Examiner	Art Unit					
	Samuel M. Heinrich	1725					
The MAILING DATE of this communication apperiod for Reply							
A SHORTENED STATUTORY PERIOD FOR REP THE MAILING DATE OF THIS COMMUNICATION  - Extensions of time may be available under the provisions of 37 CFR 1 after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a re - If NO period for reply is specified above, the maximum statutory perior - Failure to reply within the set or extended period for reply will, by statu Any reply received by the Office later than three months after the mail earned patent term adjustment. See 37 CFR 1.704(b).	N. 1.136(a). In no event, however, may a reply eply within the statutory minimum of thirty (3 d will apply and will expire SIX (6) MONTH tute, cause the application to become ABAN	oly be timely filed  (30) days will be considered timely.  HS from the mailing date of this communication.  NDONED (35 U.S.C. & 133).					
Status							
1) Responsive to communication(s) filed on							
3)☐ Since this application is in condition for allow		rs, prosecution as to the merits is					
	closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 11, 453 O.G. 213.						
Disposition of Claims	•						
4)⊠ Claim(s) <u>1-40</u> is/are pending in the applicatio	nn.						
4a) Of the above claim(s) is/are withdr							
5) Claim(s) is/are allowed.							
6)⊠ Claim(s) <u>1-40</u> is/are rejected.							
7) Claim(s) is/are objected to.	,						
8) Claim(s) are subject to restriction and	/or election requirement.	•					
Application Papers		•					
9) The specification is objected to by the Examir							
10) $\boxtimes$ The drawing(s) filed on <u>02 March 2004</u> is/are: a) $\boxtimes$ accepted or b) $\square$ objected to by the Examiner.							
Applicant may not request that any objection to the		• •					
Replacement drawing sheet(s) including the corre							
	11) The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.						
Priority under 35 U.S.C. § 119	•						
12) Acknowledgment is made of a claim for foreig	n priority under 35 U.S.C. § 1	119(a)-(d) or (f).					
a) ☐ All b) ☐ Some * c) ☐ None of:							
1. ☐ Certified copies of the priority documer							
<ul><li>2. Certified copies of the priority documer</li><li>3. Copies of the certified copies of the pri</li></ul>							
<ol> <li>Copies of the certified copies of the pri application from the International Bure</li> </ol>		sceived in this inational stage					
* See the attached detailed Office action for a lis		eceived.					
*							
Attachment(s)	1						
1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948)	4) Interview Sum	mmary (PTO-413) Mail Date					
3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08	8) 5) Notice of Info	ormal Patent Application (PTO-152)					
Paper No(s)/Mail Date <u>3/04;6/04;3/05</u> .	6) Other:						
U.S. Patent and Trademark Office PTOL-326 (Rev. 1-04) Office	Action Summary	Part of Paper No./Mail Date 06162005					

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#### DETAILED ACTION

Prosecution on the merits of this application is reopened on claims 1-40 considered unpatentable for the reasons indicated below.

## Claim Rejections - 35 USC § 112

The following is a quotation of the second paragraph of 35 U.S.C. 112:

The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.

Claims 1-40 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention. Apparatus or system claims 1-40 are described using method language limitations which may not clearly define the claimed structure.

Claim 34 recites the identical limitations which exist in claim 33.

Claim 35 describes "the laser" which has no antecedent basis in claim 32.

## Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1-40 are rejected under 35 U.S.C. 103(a) as being unpatentable over USPN 4,752,668 to Rosenfield in view of USPN 5,442,416 to Tateyama.

Rosenfield teaches the process and system for removing excess material from a semiconductor wafer employing an excimer laser. The wafer has been previously treated by treating a semiconductor with a resist, exposed, developed and selectively

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removed for the purposes of patterning various areas of the wafer. But such a manufacturing process leaves some of the resist and contaminants on the wafer. Rosenfield recognizes the need to remove the excess resist and contaminants and

provides a method and system for their removal with a laser.

Tateyama, while describing prior art, describes (Fig. 1) the method and apparatus for providing a substrate (wafer), subjecting to a preheating step (4) to remove moisture, cooled, conveyed to a coating unit where a photo-resist is evenly coated on the surface of the wafer, and the "photo-resist-coated wafer W is sent to a heating unit 8" where "the photo-resist solution on the wafer is converted into a stable film". This is the "baking" step in applicant's claims. Afterwards, the pattern is developed and excess resist material is removed.

The difference between the claimed invention and the combined teachings of Rosenfield and Tateyama is that Tateyama teaches the "prior art" recognized in Rosenfield, and Rosenfield provides the cleaning steps with a laser after the semiconductor wafer has been patterned, after a substrate (wafer) has been treated with an initial preheating, application of a resist layer on the substrate (wafer), and a baking step, according to the method of Tateyama.

Therefore, in view of the difference between the subject matter as a whole sought to be patented and the totality of the teachings of prior art, as established above, it would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains, to follow the teachings of Rosenfield and provide a step and apparatus for the removal of contaminants from a

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substrate with a laser after the substrate has been preheated (to remove moisture), coated with a resist layer and heated (baked) and patterned in the method and apparatus taught in Tateyama.

### Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Samuel M. Heinrich whose telephone number is 703 308 1168. The examiner can normally be reached on M-TH.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Thomas G. Dunn can be reached on 703 308 3318. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Samuel M. Heinrich June 16, 2005

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Samuel M Heinrich Primary Examiner Art Unit 1725